



12-03-01

1765

#8/B

la

12/10/01

1

MEMC 99-0900 (2632)  
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Fuerhoff et al.

Art Unit 1765

Serial No. 09/502,340

Filed February 10, 2000

For METHOD AND APPARATUS FOR CONTROLLING DIAMETER OF A SILICON  
CRYSTAL IN A LOCKED SEED LIFT GROWTH PROCESS

Examiner M. Anderson

October 31, 2001

AMENDMENT A

TO THE ASSISTANT COMMISSIONER FOR PATENTS,

SIR:

RECEIVED  
DEC 7 2001  
TC 1700

In response to the Office action mailed July 31, 2001, please enter the following  
amendments:

IN THE TITLE

Please replace the Title of the application with the following:

--METHOD OF CONTROLLING DIAMETER OF A SILICON CRYSTAL IN A  
LOCKED SEED LIFT GROWTH PROCESS--.

IN THE CLAIMS

Please amend claim 2 as follows:

B<sub>1</sub> 2. The method of claim 1 wherein the step of adjusting the power includes applying a  
pulse of power to the heater, said power pulse having an amplitude greater than a steady state  
value corresponding directly to the temperature set point.

Please cancel claims 11-18 without prejudice to their patentability.